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of

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Complete if Known

Application Number	New Application
Filing Date	March 31, 2004
First Named Inventor	Shunpei YAMAZAKI et al.
Art Unit	2826
Examiner Name	S. Wilson

Attorney Docket Number

740756-2719

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number - Kind Code ² (if known)	Publication Date MM-DD-YYYY		
T-D		US-5,861,656	01/19/1999	Keri	
		US-5,471,330	11/28/1995	Sarma	
		US-6,147,667	11/14/2000	Yamazaki et al	
		US-5,767,531	06/16/1998	Yoshinouchi	
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		US-6,147,667	11/14/2000	Yamazaki et al.	
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FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Foreign Patent Document		Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ³
		Country Code ⁴ Number ⁵	Kind Code ² (if known)			
T-D		JP 07-142734-A		06/02/1995	—	Abstract
		JP 58-163722-A		09/28/1983	Yabuki et al	Abstract
T-D		JP 61-070780-A		04/11/1986	Oda et al	Abstract

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
T-D		Lim et al. "High Performance Amorphous Silicon Thin Film Transistor with a Planarized SiN _x /BCB Double-Layered Gate Insulator", AM-LCD '98 pp. 73-76	
T-D		Won et al. "28.3: A High-Resolution Full Color TFT-LCD on Transparent Plastic", SID '03 DIGEST, pp. 992-995	
T-D		Jang et al. "32.1: Invited Paper: Amorphous Silicon Thin-Film Transistors with Planarized Gate Insulators" (4 pages)	
T-D		Wolf, Silicon Processing for the VLSI Era, 1990, Lattice Press, Volume 2, p. 273-274, 354, 356-357, 359.	

Examiner Signature	T. DANF	Date Considered	1/06/2005
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Applicant's unique citation designation number (optional). ² See Kinds Codes of USPTO Patent Documents at www.uspto.gov or MPEP 901.04. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST.16 if possible. ⁶ Applicant is to place a check mark here if English language Translation is attached